SEMICONDUCTOR PROCESSING CHAMBER

ABSTRACT

A semiconductor processing chamber includes a chamber having an opening at a top of the chamber, a housing disposed above the opening, a dielectric window disposed inside the housing and above the opening, a coil arranged circumferentially at an inner top wall of the housing; and a hot air hood disposed inside the housing and fixedly attached to the dielectric window for heating the dielectric window, where the hot air hood and the inner top wall of the housing are separated by a clearance gap.

FIG. 5